



PATENT  
DOCKET NO.: 29273/502

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS : Hajime KAWANO, et al.  
SERIAL NO. : 09/315,988  
FILED : 21 May 1999  
FOR : ELECTRON BEAM LITHOGRAPHY SYSTEM  
Patent No. : **6,828,573 B1** Issued 07 December 2004

COMMISSIONER FOR PATENTS  
Customer Service Window  
Randolph Bldg.  
401 Dulany Street  
Alexandria, VA 22314

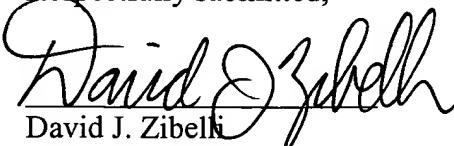
**REQUEST FOR CERTIFICATE OF CORRECTION**  
**PURSUANT TO 37 C.F.R. § 1.322**

SIR:

It is respectfully requested that the enclosed certificate of correction be issued for the above Patent under authority of 35 USC §354.

The change represents correction of an error which occurred during printing of the patent and was not the fault of the applicants. Therefore, no fee is required.

Respectfully submitted,

  
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Dated: 03 May 2005

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UNITED STATES PATENT AND  
TRADEMARK OFFICE  
CERTIFICATE OF CORRECTION

**PATENT NO.** : US 6,828,573 B1 Page 1 of 1  
**DATED** : 07 December 2004  
**INVENTOR(S)** : Hajime KAWANO, et al.

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

<b><u>Column</u></b>	<b><u>Line</u></b>	
12	19	Change "N <sub>a</sub> /2." to --N <sub>s</sub> /2.--.

**MAILING ADDRESS OF SENDER:** Patent No.: 6,828,573 B1

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